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Optical Measurement Systems for Industrial Inspection XIV

Peter Lehmann Wolfgang Osten Armando Albertazzi Gonçalves Jr. Editors

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Contents

ix Conference Committee

xi Introduction

OPTICAL METROLOGY PLENARY SESSION

13567 02 The wide-scale range of optical measurement technology and its exploration (Plenary Paper) [13567-500] **DIGITAL HOLOGRAPHY** 13567 04 Digital holography for shape measurement of a moving object [13567-2] 13567 05 Multi-wavelength holography with flexible synthetic wavelengths [13567-3] 13567 06 Multi-wavelength varifocal common-path configuration for digital holographic microscopy [13567-4] STRUCTURED LIGHT AND FRINGE PROJECTION 13567 08 Approach for assessing compressor blade leading edge damage without CAD model **reference** [13567-6] 13567 09 In situ optical 3D sensor for precise extrusion die measurement [13567-7] Temporally super-resolved multiplexed fringe projection structured light 3D imaging 13567 0A empowered by deep learning [13567-8] 13567 0D Multidevice versus mirror-based system for 360-degrees fringe projection profilometry [13567-11] **INTERFEROMETRY** Inspection of linear axicon surface by double-pass interferometry [13567-12] 13567 OE 13567 OF Development of dual-wavelength polarization interferometer for profile measurement of rough surface [13567-13]

13567 OG	Waveplates retardance multispectral metrology with a Wollaston prism generated fringe field [13567-14]
13567 OH	Ultrasensitive nonlinear phase metrology [13567-15]
	IN-SITU AND IN-LINE MEASUREMENT
13567 OL	Robot-assisted high-dynamic-range optical measurement [13567-19]
13567 OM	Observation of laser-generated ultrasound for in-process control of laser processing [13567-20]
	SHEAROGRAPHY AND NONDESTRUCTIVE TESTING
13567 ON	OpenSpeckle: open science principles in shearography and ESPI [13567-21]
13567 00	Reliable full-field reconstruction of Lamb waves with shearography [13567-22]
13567 OP	A flexible three-directional shearography module attachable to a high-resolution digital still camera [13567-23]
13567 0Q	100 MHz SPML-OCT for high-throughput inspection [13567-24]
	LOW-COHERENCE INTERFEROMETRY, CONFOCAL SENSING, AND CALIBRATION
13567 OS	Additively manufactured material measures for resolution determination in optical surface texture measurement [13567-26]
13567 OT	Time-domain full-field optical coherence tomography as an interferometry-based measurement system for analyzing droplet geometry and dynamics on structured surfaces [13567-27]
13567 OU	Influence of scattering and steepness in optical component characterization using optical coherence tomography (OCT) [13567-28]
13567 OV	Phase-modulated differential confocal microscopy with compensating algorithm against specimen-induced aberration [13567-29]
13567 OX	1D line-scan imaging of gold nanoparticles beyond diffraction limit with white light via absorbance modulation nanoscopy [13567-31]
13567 OY	Confocal versus interference microscopy: 3D resolution analysis [13567-32]

JOINT SESSION: QUANTITATIVE MICROSCOPY

	JOINT SESSION: QUANTITATIVE MICROSCOPY
13567 10	Multifunctional coherence scanning interferometric microscopy and measuring techniques [13567-34]
	MICROSPHERE-ASSISTED MICROSCOPY
13567 11	Range-resolved interferometry for metrological measurements using retroreflective microspheres [13567-35]
13567 12	Comparison of microcylinder and microsphere assistance in interferometry: simulation and experiments [13567-36]
	LIDAR TECHNIQUES
13567 14	Sensitivity of beam expander optical elements in a dynamic beam steering system [13567-39]
13567 15	A fiber-optic LiDAR sensor for navigation in confined spaces [13567-40]
13567 16	A Monte Carlo model for analyzing the propagation of polarized TOF-LIDAR pulses through turbid media [13567-41]
13567 17	Design and construction of a multimodal perception system based on LiDAR for underwater applications [13567-42]
13567 18	A UAV-mounted dual-wavelength LiDAR for leaf water content retrieval [13567-38]
	SPECIAL SESSION: MEASUREMENT SYSTEMS FOR UAVS AND SATELLITES
13567 19	Improved BRDF metrology platform for Copernicus CO2I FCU calibration [13567-43]
13567 1A	Uncertainty evaluation for a drone-based laser triangulation system [13567-44]
13567 1B	Fiber-optic shape sensing for motion compensation in vibration-prone optical measurements [13567-45]
13567 1C	Drone-based single-shot fault detection method for wind turbines: conception and initial feasibility study [13567-46]
13567 1D	Differential laser Doppler vibrometry with integrated alignment camera to reduce disturbances in airborne vibration measurements with a UAV [13567-47]

DYNAMIC AND THERMAL MEASUREMENT

13567 1E	Dynamical system regularized object positioning from diffraction movie [13567-49]
13567 1F	Thermal light section sensor for real-time 3D measurement of transparent objects [13567-50]
13567 1G	A comparative study of measurement capabilities of two large-space measurement systems: iGPS and OptiTrack [13567-96]
	LIGHT SCATTERING TECHNIQUES
13567 11	Implementation of quad detection scheme in coherent Fourier scatterometry for inspection of patterned structures [13567-53]
13567 1J	Inline surface analysis through combined evaluation of scattering and geometric properties: exemplary possibilities for integration in bipolar plate production [13567-54]
13567 1K	Scatterometric defect detection of nanowire surfaces: evaluating the effect of sensor position density [13567-55]
13567 1M	SWIR oblique-scanning scatterometry with global sensitivity analysis and back focal plane imaging for hidden HAR microstructure critical dimension measurement [13567-57]
	MEASUREMENT OF PRECISION COMPONENTS
13567 1N	Absolute testing for cylindrical surface [13567-63]
13567 10	Angle-resolved chromatic confocal microscopy for accurate free-form surface reconstruction employing back focal plane projection and ANN modeling [13567-58]
13567 1P	Non-contact metrology of datum surfaces and fiducials on freeform telescope mirrors [13567-59]
13567 1Q	Performance evaluation of the first modules of the of the gradient-phase interferometer within the ELT M1 Local Coherencer [13567-60]
13567 1R	Compact AR-HUD optical evaluation system using MTF measurement [13567-61]
13567 1T	Optical metrology for mass production of microLED displays & wafers [13567-69]
13567 1U	Development of a 5D nanopositioning and nanomeasuring machine concept for precise measurement and fabrication of complex free-form surfaces [13567-64]

CHARACTERIZATION OF OPTICAL MATERIALS AND COMPONENTS

13567 1V	Characterizing and reporting effects of refractive index homogeneity structure to lens assembly performance [13567-65]
13567 1W	Design and measurement techniques of essential parameters for all-silica step-index fibers for demanding applications [13567-66]
13567 1X	Birefringence metrology analysis for CaF ₂ [13567-67]
13567 1Y	Characterization of femtosecond laser-structured materials using interference microscopy: local spectroscopy, colorimetry, and topography [13567-68]
	POSTER SESSION
13567 1Z	Advanced speckle methods with high-speed imaging for impact testing of composites [13567-52]
13567 21	FMCW-digital holography for utilizing the spatiotemporal frequency domain as a multiplexable bandwidth: simultaneous two-wavelength profile measurement for multiple objects [13567-71]
13567 22	Enhancing measurement stability in ultra-precise angular deflection sensors via cylindrical lens correction [13567-72]
13567 23	Cost-effective BRDF spectroscopic bench involving gimbal-based sample positioning system [13567-73]
13567 24	Comparison of two technologies for the automated optical inspection (AOI) of PCBs [13567-74]
13567 25	Using confocal scanning for the definition of a relation between physical and equivalent roughness in hydraulic concrete pipes [13567-75]
13567 26	Precision inspection of transparent optical materials quality by interferometry [13567-76]
13567 27	Cheap targets for expensive equipment: a novel, integrated, high-contrast approach to LWIR camera calibration [13567-77]
13567 28	Methodology to manufacturing and testing freeform aluminum mold [13567-78]
13567 29	Deep learning assisted fringe normalization for handling dynamic intensity fluctuations in digital holographic interferometry [13567-79]
13567 2B	Temporal defect identification using deep learning method in digital holographic interferometry [13567-81]

13567 2C	Dielectric hollow core glass-waveguide-based cavity-enhanced trace gas analysis for inline measurement of methane using mid-infrared interband cascade LED [13567-82]
13567 2D	Wavefront error characterization of SurfCam using interferometry for lunar surface imaging [13567-83]
13567 2E	Multimodal sensing prototype for robust autonomous driving under adverse weather conditions [13567-84]
13567 2F	Experimental analysis of additive manufactured particle damping structures for vibration-sensitive optical systems [13567-85]
13567 2H	Non-contact anisotropic roughness measurement with the generalized Harvey-Shack theory [13567-89]
13567 21	Limits of detection of defects near edges of nanostructures for coherent Fourier scatterometry [13567-90]
13567 2J	Aberration characterisation in coherent Fourier scatterometry [13567-92]
13567 2K	Model-based uncertainty correction for raycasting-based image projection onto 3D reference geometries [13567-95]
13567 2L	Validation of optical surface texture measurements on a milled technical surface using a stylus profilometer [13567-97]
13567 2M	Free-space testbed for interferometric spacecraft-to-spacecraft laser ranging acquisition [13567-98]
13567 2N	Fringe value measurement of intrinsic-birefringent flexible substrate [13567-99]
13567 20	Wavelet transform for surface roughness measurement using laser speckle imaging technique [13567-100]
13567 2P	Heat flow visualization and thermal anomaly detection using phase measuring deflectometry [13567-101]
13567 2Q	Broadband multi-LED reference emitter for the high-speed calibration of non-contact temperature measuring devices [13567-103]
13567 2R	Design of high impact resistance micro-hemispherical resonators for optical measurement systems in industrial inspection [13567-104]
13567 2S	Fiber feedback controlled, power and spectral regulated high power laser module for laser welding [13567-105]